

Docket Number: 081468-0308089

PATENT APPLICATION

Client Reference: P-1500.010-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

FLAGELLO et al.

Group Art Unit: TBA

Application No.: NEW

Examiner: TBA

Filed: February 26, 2004

Confirmation No.: TBA

For: Stationary and Dynamic Radial Transverse Electric Polarizer for High Numerical Aperture Systems

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

The undersigned respectfully notes that copies of U.S. references are not required in applications filed after June 30, 2003. Copies of the references cited in parent application, 10/374,509, on which this application relies for priority under 35 U.S.C. § 120 are not provided. See 37 C.F.R. § 1.98(d).

This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,



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Date: February 26, 2004
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M#

Client Ref.

308089

P-01500.010-US

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: FLAGELLO et al.

**Continuation-In-Part of Appln. No.: 10/374,509 filed
February 27, 2003**

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Examiner: Unassigned

Group Art Unit: Unassigned

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	3,998,524	12/1976	HUBBY, Jr. et al.			
	BR	4,384,760	05/1983	ALFERNES			
	CR	5,383,053	01/1995	HEGG et al.			
	DR	6,288,840	09/2001	PERKINS et al.			
	ER	6,392,800	05/2002	SCHUSTER			
	FR	6,452,724	09/2002	HANSEN et al.			
	GR	6,122,103	09/2000	PERKINS et al.			
	HR	6,191,880 B1	02/2001	SCHUSTER			
	IR	5,523,193	06/1996	NELSON			
	JR	5,296,891	03/1994	VOGT et al.			
	KR	5,229,872	07/1993	MUMOLA			
	LR	6,046,792	04/2000	VAN DER WERF et al.			

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract	Translation Readily Available
							Enclosed	No
	MR	98/38597	09/1998	WIPO	Thuren			
	NR	98/33096	07/1998	WIPO	Sandstrom et al.			

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	OR	Flagello et al., "Theory of high-NA imaging in homogeneous thin films," <i>J. Opt. Soc. Am. A</i> 13(1):53-64 (1996)			
	PR	Lopez et al., "Wave-plate polarizing beam splitter based on a form-birefringent multilayer grating," <i>Optics Letters</i> 23(20):1627-1629 (1998)			
	QR	Ferstl et al., "High-frequency gratings as polarization elements," <i>Part of the SPIE Conference on Micromachine Technology for Diffractive and Holographic Optics</i> 2879:138-146 (1999)			
	RR	Flagello et al., "Optical Lithography into the Millenium: Sensitivity to Aberrations, Vibration and Polarization," <i>SPIE The 25th Annual International Symposium on Microlithography</i> , February 27-March 3, 2000, Santa Clara, CA, pp. 1-12			
	SR	Switkes et al., "Immersion lithography at 157 nm," <i>J. Vac. Sci. Technol. B</i> 19(6):2353-2356 (2001)			
	TR	Bomzon et al., "Radially and azimuthally polarized beams generated by space-variant dielectric subwavelength gratings," <i>Optics Letters</i> 27(5):285-287 (2002)			
	UR	Mulkens et al., "157-nm Technology: Where are we Today?," <i>SPIE The 27th Annual Symposium on Microlithography</i> , March 3-8, 2002, Santa Clara, CA, pp. 1-11			

Examiner

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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Examiner: Unassigned

Group Art Unit: Unassigned

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Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	6,288,840 B1	09/2001	PERKINS et al.			
	BR	6,262,796 B1	07/2001	LOOPSTRA et al.			
	CR	5,969,441	10/1999	LOOPSTRA et al.			
	DR						
	ER						
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	JR						
	KR						
	LR						
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	NR						
	OR						

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